

Helios

Plasma Enhanced Chemical Vapor Deposition Systems

Features

- Batch Process
- Substrate sizes up to 31" x 61"
- Doors open on both ends for easy access
- High quality stainless steel or aluminum chambers
- Harsh duty dry pump for process gases
- Fully automated, state of the art process control
- Real-time remote monitoring
- Graphical user interface
- Clean room compatible
- Turbomolecular pumping

Options

- Very high frequency RF (40.68 MHz)
- Preheat and cool down chambers
- Carrier carts

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Customer Service & Support

- World-wide support
- Expert process analysis and engineering
- Real-time remote process and service support
- Over 45 years experience in thin films

